Docket No.: 5545 (2616-012)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application Commissioner for Patents Washington, D.C. 20231

Re:

Inventors: Gene H. LEE, Nam-Hun KIM

Method for Etching Tungsten Using NF 3 and Cl 2

Transmitted herewith is the patent application identified above, including:

X Specification, claims and abstract, totaling 20 pages.

X Drawings totaling 4 pages, Formal X Informal.

<u>X</u> Executed Declaration and Power of Attorney.

Assignment of the invention to Applied Materials, Inc.

Information Disclosure Statement (37 C.F.R. § 1.98)



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Assignment of the invention to Applied Assignment Recordation Cover Sheet Information Disclosure Statement (37 C FEE CALCULATION

Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	21	-20=	1	X\$18.00	\$ 18.00
Independent Claims	3	-3=	0	X\$84.00	\$ 0.00
Basic Filing Fee				\$740.00	\$740.00
TOTAL FEES					\$758.00

XXThe Commissioner is hereby authorized to charge \$758.00 to Deposit Account No. 50-1074.

XXThe Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. <u>50-1074</u>. A duplicate copy of this transmittal is enclosed.

XXPlease address all future correspondence to: PATENT COUNSEL APPLIED MATERIALS, INC. **Legal Affairs Department** P.O. BOX 450A

Santa Clara, CA. 95052

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231.

EL661803784US

Robert W. Mulcahy Registration No. 25,436

Respectfully submitted